

FIG. 1

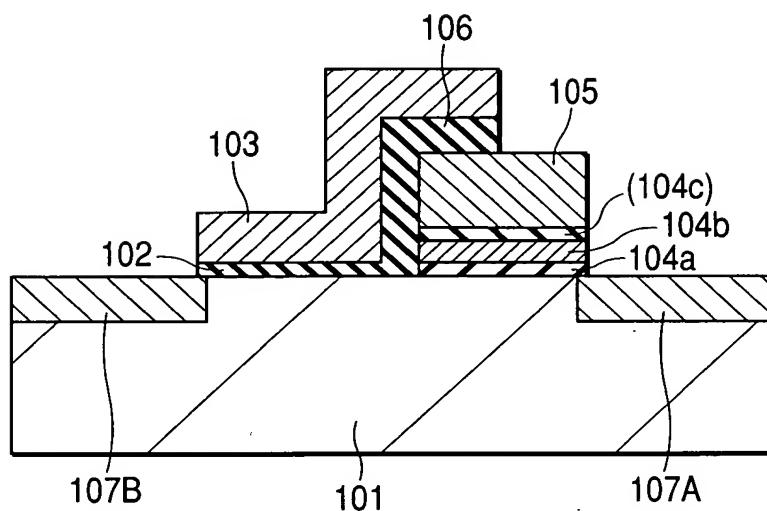


FIG. 2

	V _{sg}	V _{mg}	V _s	V _d	V _{well}	METHOD (TECHNIQUE)
WRITE (INJECTION)	~V _t	10V	5V	0V	0V	SOURCE SIDE INJECTION
ERASE (DISCHARGE)	0V	VARIABLE	0V	0V	0V	TUNNELING
READ	1.8V	0V	0V	1.8V	0V	REVERSE READ
	1.8V	0V	1.8V	0V	0V	FORWARD READ

FIG. 3

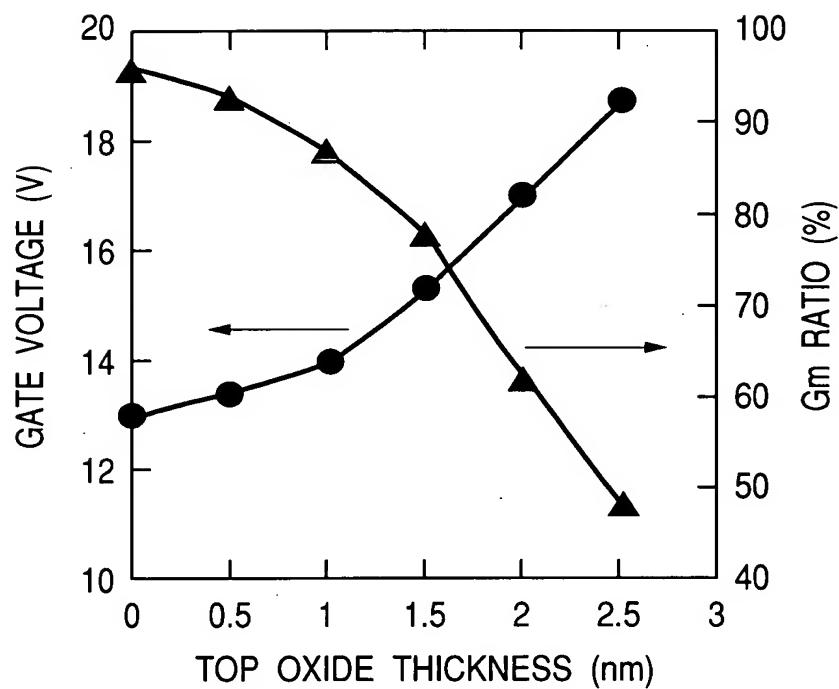


FIG. 4

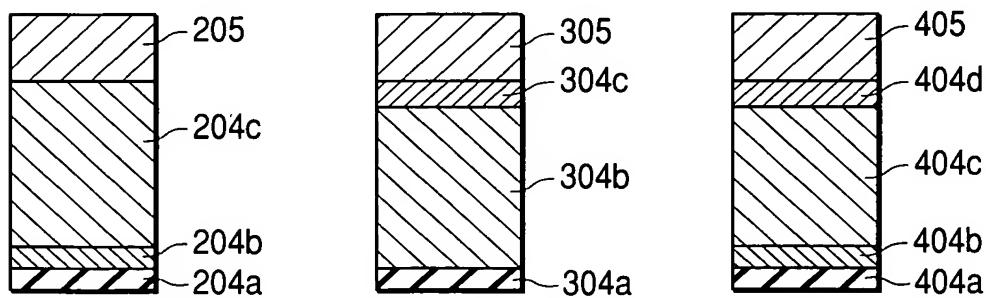


FIG. 5

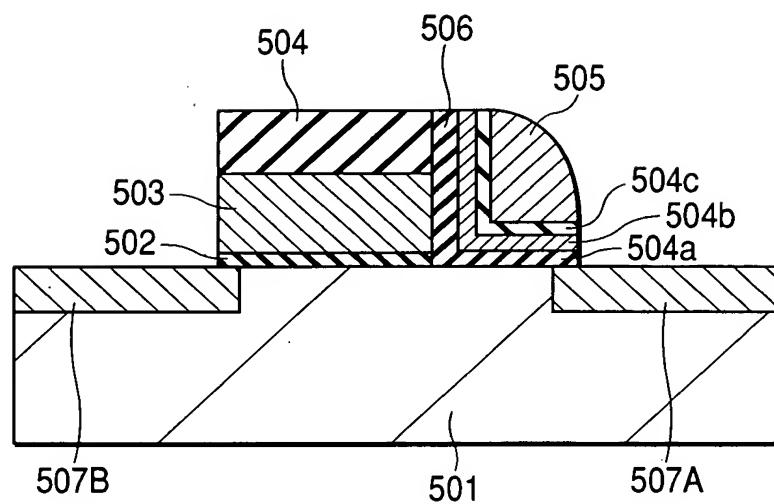


FIG. 6

	V _{sg}	V _{mg}	V _s	V _d	V _{well}	METHOD (TECHNIQUE)
WRITE (INJECTION)	~V _t	10V	5V	0V	0V	SOURCE SIDE INJECTION
ERASE (DISCHARGE)	0V	-6V	0V	5~7V	0V	(HOT HOLE INJECTION)
READ	1.8V	0V	0V	1.8V	0V	REVERSE READ
	1.8V	0V	1.8V	0V	0V	FORWARD READ

FIG. 7

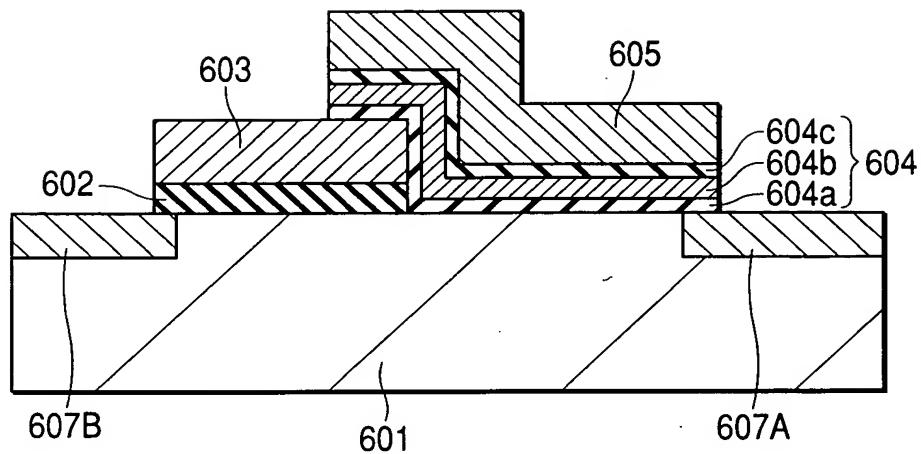


FIG. 8

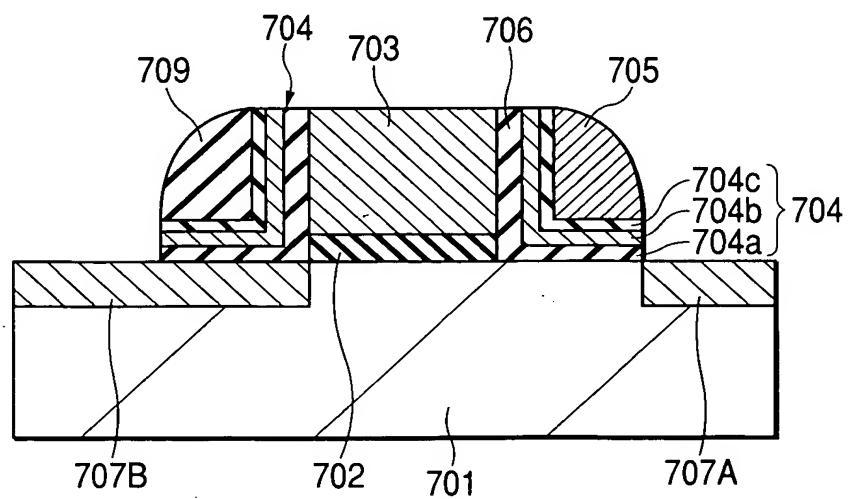


FIG. 9

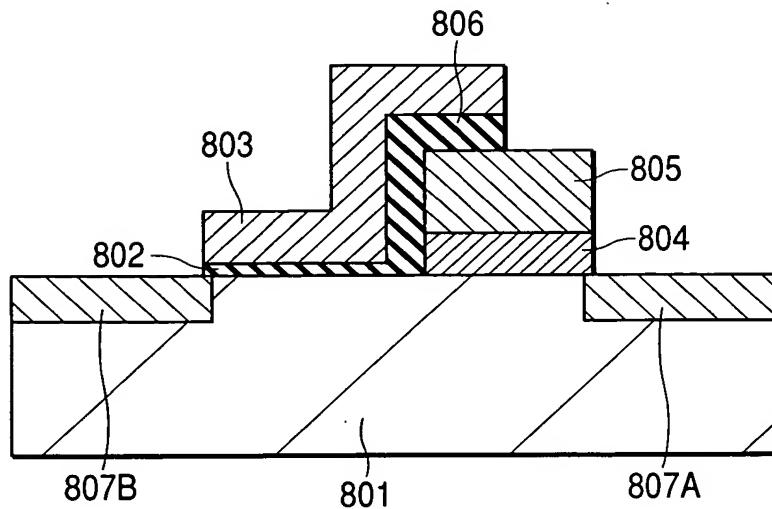


FIG. 10

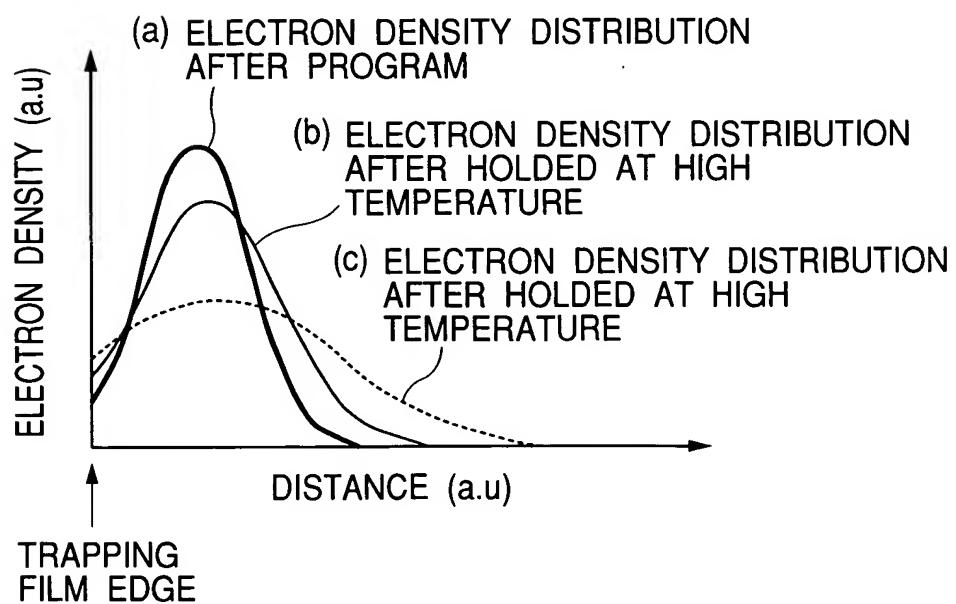


FIG. 11

	STACK FILMS STRUCTURE	MAIN TRAPPING FILM	POTENTIAL BARRIER FILM	OXYGEN CONCENTRATION OF SiON FILM
1	SiO ₂ /SiON	SiON	NONE	
2	SiO ₂ /SiON/SiO ₂	SiON	SiO ₂	
3	SiO ₂ /SiON/SiN	SiON	NONE	
4	SiO ₂ /SiN/SiON	SiON	NONE	
5	SiO ₂ /SiON(1)/SiON(2)	(a) SiON(1)	NONE	SiON(1)>SiON(2)
		(b) SiON(2)	NONE	
6	SiO ₂ /SiN(1)/SiON/SiN(2)	SiON	NONE	
7	SiO ₂ /SiON(1)/SiN/SiON(2)	(a) SiON(1)	NONE	SiON(1)>SiON(2)
		(b) SiON(2)	NONE	

FIG. 12

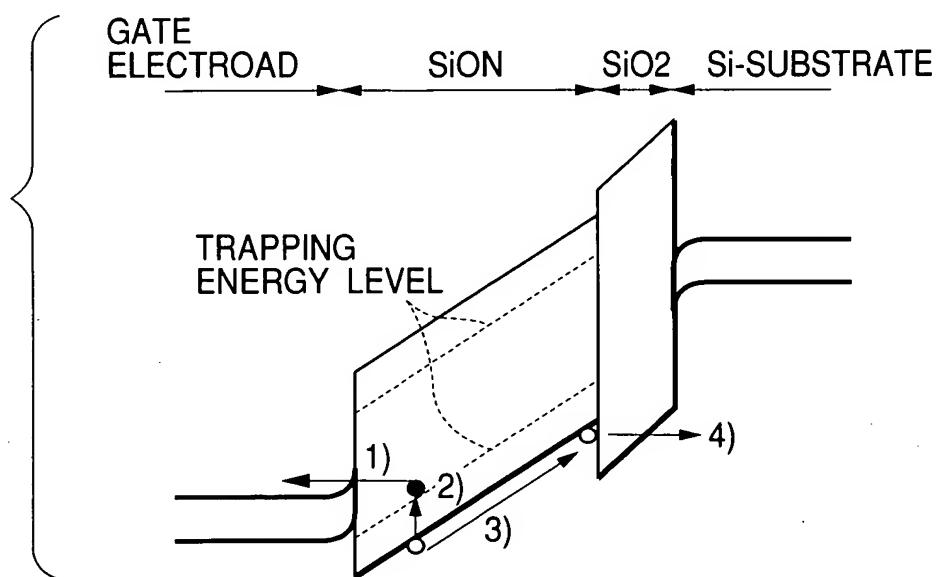


FIG. 13

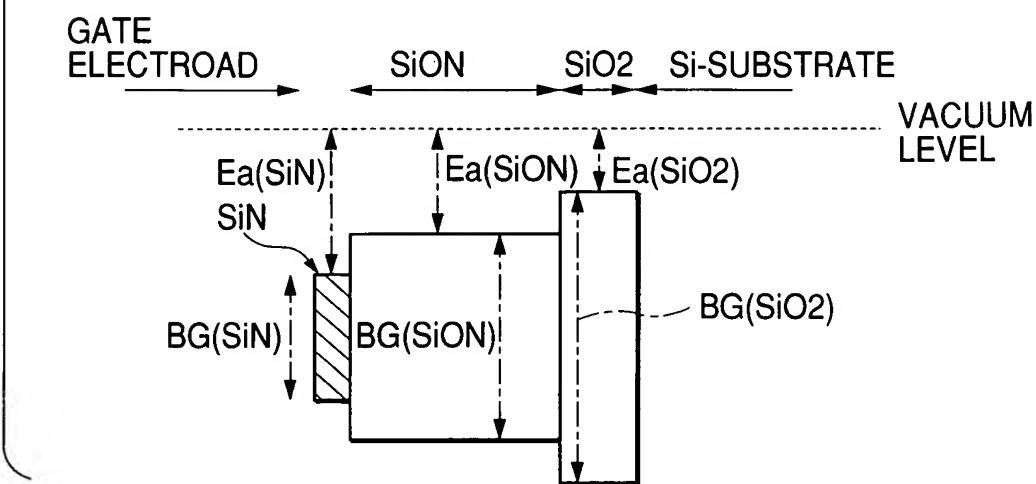
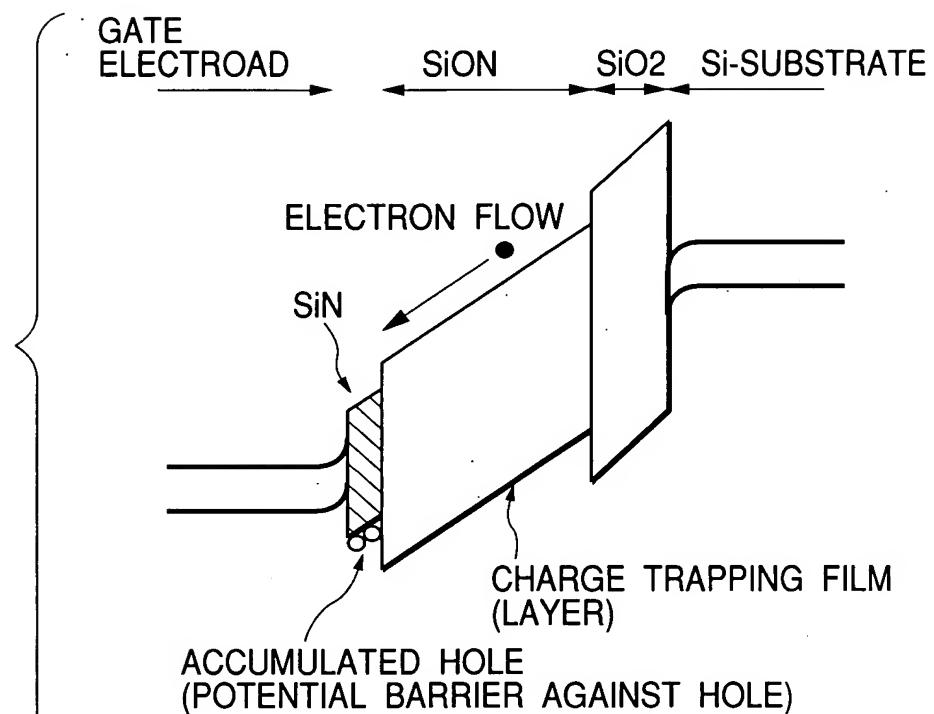


FIG. 14

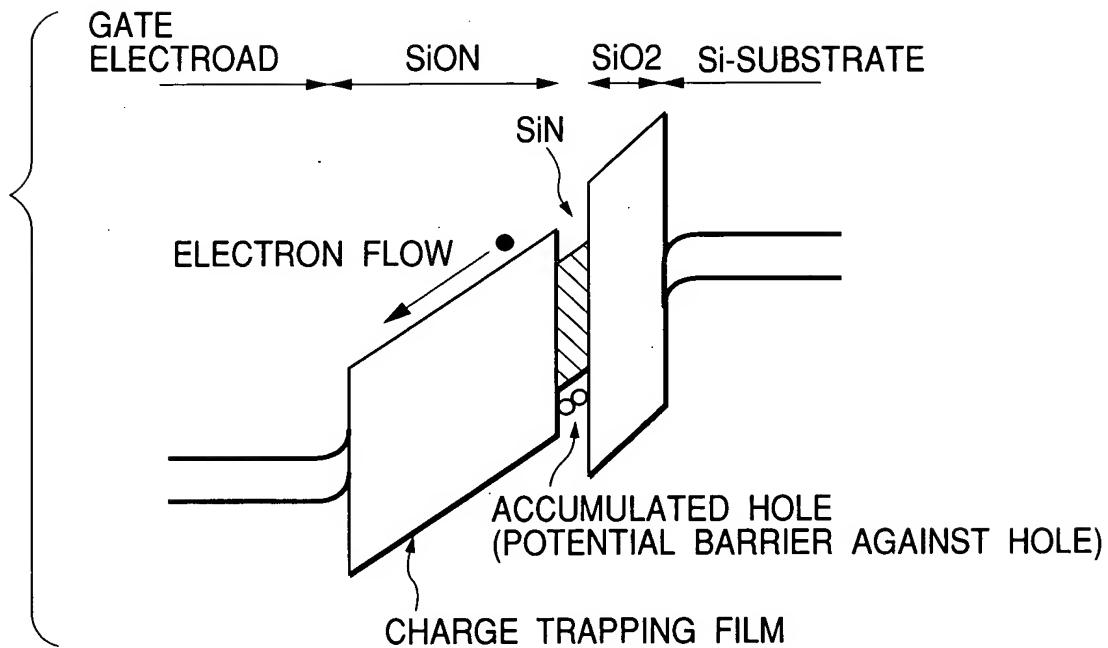


FIG. 15

